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Docket: P910270

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Chen et al.

U.S. Serial No: 10/661,089


Filed: September 10, 2003

For: METHOD FOR MITIGATING
CHEMICAL VAPOR DEPOSITION/
PHOSPHORUS DOPING OXIDE
SURFACE INDUCED DEFECTS

/
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/ Examiner: Tran, Mai Huong C.
/
/ Group Art: 2818
/
/
/

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service, First Class mail, postage prepaid, in an envelope addressed to Mail Stop Non-Fee Amendment, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on December 8, 2004.
STOUT, UXA, BUYAN & MULLINS, LLP


Kenton R. Mullins, Reg. No. 36,331

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

Responsive to the Examiner's Office Action of November 9, 2004, Applicants hereby elect without traverse the invention of Group II as outlined by the Examiner, comprising Claims 1-17 which are drawn to a process of making a semiconductor device, classified in class 438, subclass 778.

Applicants respectfully submit that the application is now in condition for a first action on the merits, and request that such be done at an early date. Should the Examiner believe that a telephone conference with Applicants' representative would be helpful to advance the prosecution of the application, he is invited to contact the undersigned with any questions.

Respectfully submitted,



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